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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Maki TANAKA et al.
Serial No.: 09/942,213
Filed: August 30, 2001
For: **METHOD AND APPARATUS FOR INSPECTING A
SEMICONDUCTOR DEVICE**
Group: 2625
Examiner: John B. Strege

AMENDMENT

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 18, 2004

Sir:

In response to the Office Action (Paper No. 8) dated on August 23, 2004,
please amend the above-identified application as follows.

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 8 of this paper.